



Advanced (*Citius, Minor, Simplicius*) Laser Fabrication Technologies for Cross-Field Applications

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Message from the Guest Editors

This Special Issue aims to highlight the latest developments in advanced laser fabrication technologies and novelty applications such as micro/nano-optics, photonic integrated circuits, micro/nano-robotics, etc., with development towards green energy and bio-medical fields for the strongest societal impact.

Potential topics include, but are not limited to:

1. Etching (plasma, wet bath) assisted laser fabrication technology.
2. Laser processing technology with light field modulation (far-field (Gaussian, Bessel), near-field).
3. Laser-induced micro/nanostructures.
4. 3D/4D printing based on the laser fabrication technique.
5. Creation of new materials and composites on interfaces of photo-electrode sensor surfaces by controlled phase transitions.
6. Materials for green energy applications (solar cell patterning, hydrogen-producing photo-electrodes, batteries, fuel cells).

We seek submissions where the cross-disciplinary use of different fabrication techniques are combined, especially where such combination opens new applications in bio-medical, environmental sensor, green energy, photo-/electro-catalysis, and battery applications.





Editor-in-Chief

Message from the Editor-in-Chief

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